L Number	Hits Search Text	DB	Time stamp
5	4 (coat coating deposit depositing	USPAT;	2003/05/21 09:56
i i	deposition film layer layering) near3	US-PGPUB;	1
	(silicon near (carbide nitride oxide	EPO; JPO;	1
1	dioxide) "si.sub.3.N.sub.4" "si.sub.3	DERWENT;	1
	n.sub.4" "sio.sub.2" "si O.sub.2" "SiC"	IBM_TDB	
	"Si C") and ((438/121,122,for.436).CCLS.)	_	l i
	and @pd>=20030204		1